



PATENT

MON. 140DV1C1

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	: Weimin Li et al.	Group Art Unit 1734
Appl. No.	: 10/757,638	
Filed	: January 13, 2004	
For	: TECHNIQUE FOR HIGH EFFICIENCY METALORGANIC CHEMICAL VAPOR DEPOSITION	
Examiner	: Unknown	

REQUEST FOR CORRECTED FILING RECEIPT

Commissioner for Patents  
P.O. Box 1450  
Office of Initial Patent Examination  
Customer Service Center  
Alexandria, VA 22313-1450

Dear Sir:

Applicants hereby request that the Official Filing Receipt, a copy of which is enclosed, be corrected to reflect the correct title: "Technique for high efficiency metalorganic chemical vapor deposition". Presently, the Filing Receipt incorrectly shows the title as "Technique for high efficiency metaloganic chemical vapor deposition".

Respectfully submitted,

KNOBBE, MARTENS, OLSON &amp; BEAR, LLP

Dated: 5/7/2004

By:

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MICRON.140DV1C1 QSC  
MHT/LHL

## UNITED STATES PATENT AND TRADEMARK OFFICE

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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/757,638	01/13/2004	1734	770	MICRON.140DV1C1	6	20	2

20995

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CONFIRMATION NO. 4659

## FILING RECEIPT



\*OC000000012392567\*

Date Mailed: 04/19/2004

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE; NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Filing Receipt Corrections, facsimile number 703-746-9195. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

## Applicant(s)

Weimin Li, Boise, ID;  
Sam Yang, Wappingers Falls, NY;

## Domestic Priority data as claimed by applicant

This application is a CON of 10/234,729 08/30/2002 PAT 6,676,756  
which is a DIV of 09/945,567 08/30/2001 PAT 6,576,538

## Foreign Applications

If Required, Foreign Filing License Granted: 04/19/2004

Projected Publication Date: 07/29/2004

Non-Publication Request: No

Early Publication Request: No

## Title

metalorganic  
Technique for high efficiency metalorganic chemical vapor deposition

**Preliminary Class**

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Title 35, United States Code, Section 184  
Title 37, Code of Federal Regulations, 5.11 & 5.15**

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